

MODEL **1040** NanoMill® TEM Specimen Preparation System

The NanoMill system uses an ultra-low energy, concentrated ion beam to produce the highest quality specimens for transmission electron microscopy.

Model 1040 NanoMill [®] TEM Specimen Preparation System Specifications	
lon source	Filament-based ion source combined with electrostatic lens system
	Variable voltage (50 eV to 2 kV), continuously adjustable
	Beam current density up to 1 mA/cm ²
	Beam diameter as small as 1 µm at 2,000 eV
	Faraday cup for ion beam current monitoring with a range of 1 to 2,000 pA
	Field-replaceable apertures
Specimen stage	Load lock allows specimen exchange in less than 10 seconds
	Transfer rod for specimen exchange
	Milling angle range of -12 to $+30^{\circ}$
Vacuum system	Turbomolecular drag pump backed by an oil-free diaphragm pump
	Chamber vacuum measurement with a combination cold cathode and Pirani gauge with a range of atmosphere to 1 x 10 ⁻⁸ mbar
	System base vacuum of 3 x 10 ⁻⁷ mbar
	Operating vacuum of 1 x 10 ⁻⁴ mbar
Gas	Automated using mass flow control technology
	Flow rate up to 2 sccm
	Integral particulate filter
	Inert gas (argon) with recommended purity of 99.999%

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Specimen targeting	lon beam capable of being targeted at one spot on the specimen surface or scanned within a selected area
User interface	Menu-driven interface
	Programmable milling cycles with system status displayed
Chamber illumination	User-controlled chamber illumination to facilitate specimen exchange
Specimen cooling	Liquid nitrogen conductive cooling with automatic temperature interlocks
	Stage temperature to -170 °C
	System cool-down time less than 20 minutes
	Specimen cool-down time less than 5 minutes
	Dewar hold time up to 6 hours
	Integral load lock heater ensures rapid specimen warming times to ambient temperature
Automatic termination	Process termination by time or temperature
Imaging	SED-based imaging technology
Imaging	SED-based imaging technology 3 mm field of view
Imaging	SED-based imaging technology 3 mm field of view Everhart-Thornley detector
Imaging	SED-based imaging technology 3 mm field of view Everhart-Thornley detector Specimen image displayed on graphical user interface
Imaging Dimensions	SED-based imaging technology 3 mm field of view Everhart-Thornley detector Specimen image displayed on graphical user interface 39 in (991 mm) width x 58 in (1,474 mm) height x 31 in (788 mm) depth
Imaging Dimensions Weight	SED-based imaging technology 3 mm field of view Everhart-Thornley detector Specimen image displayed on graphical user interface 39 in (991 mm) width x 58 in (1,474 mm) height x 31 in (788 mm) depth 507 lb (230.5 kg)
Imaging Dimensions Weight Power	SED-based imaging technology 3 mm field of view Everhart-Thornley detector Specimen image displayed on graphical user interface 39 in (991 mm) width x 58 in (1,474 mm) height x 31 in (788 mm) depth 507 lb (230.5 kg) 110/220 V AC, 50/60 Hz, 1,000 W
Imaging Dimensions Weight Power Warranty	SED-based imaging technology 3 mm field of view Everhart-Thornley detector Specimen image displayed on graphical user interface 39 in (991 mm) width x 58 in (1,474 mm) height x 31 in (788 mm) depth 507 lb (230.5 kg) 110/220 V AC, 50/60 Hz, 1,000 W One year

Distribution in the UK & Ireland



Characterisation, Measurement & Analysis

Lambda Photometrics Limited Lambda House Batford Mill Harpenden Herts AL5 5BZ United Kingdom

- E: info@lambdaphoto.co.uk
- W: www.lambdaphoto.co.uk
- T: +44 (0)1582 764334
- F: +44 (0)1582 712084

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